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On 1-13-03

TOWNSEND and TOWNSEND and CREW LLP

By: Linda Shaffer

Attorney Docket No.: 18564-005810

PATENT

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re application of:

Chang-Meng Hsiung

Application No.: 09/660,138

Filed: September 12, 2000

For: MEASURING CONDUCTING  
PATHS USING INFRARED  
THERMOGRAPHY

Examiner: Brian J. Sines

Art Unit: 1743

AMENDMENT

Assistant Commissioner for Patents  
Washington, D.C. 20231

RECEIVED  
JAN 23 2003  
TC 1700

Sir:

In response to the Office Action mailed September 11, 2002, please amend the above-identified application as follows. A petition for a one-month extension of time accompanies this response.

IN THE CLAIMS:

Please amend claims 19 and 22 as follows:

1                   19. (Amended) A method for monitoring the quality of a sensor,  
2 comprising:  
3                   applying a voltage to said sensor to cause said sensor to dissipate energy;  
4                   capturing an image of said sensor with an infrared camera to generate a  
5                   thermographic image of said sensor while said sensor is dissipating energy;